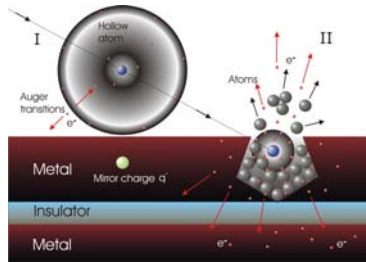


## Goals

- Investigation of electronic excitations at and below the surface due to energy dissipation of highly charged ions
- Measurement of characteristic parameters of emitted particles with respect to localized electronic excitations
- Possible interaction between kinetic and potential effects
- Characterization of energy transfer processes by different kinds of energy dissipation

## Scenario of Ion Impact at Surfaces

- Approach of the ion with well defined charge state, mass, kinetic and potential energy
- Development of a mirror charge below the surface and transition of electrons from the surface to highly excited states - "hollow atoms" (figure part I)
- Partial deexcitation of the projectile - electron emission ("pumping") by Auger transitions
- Impact of the ion; sputtering of electrons, ions and neutrals; complete deexcitation below the surface (figure part II)

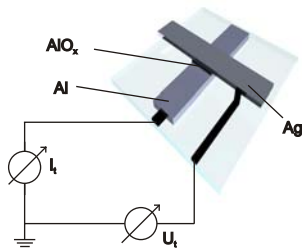


## Experiment

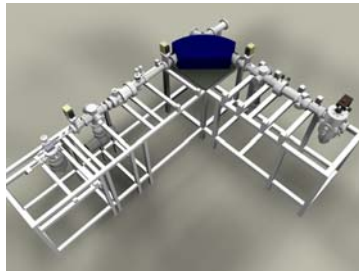
### Detection of Hot Electrons

with thin film metal-insulator-metal junctions

- Measurement of hot electrons:** excited electrons will move through the insulator and can be measured in the bottom electrode
- Energy dependence:** investigation of electron energy by application of a bias voltage between the two electrodes



### The Beamline in Duisburg

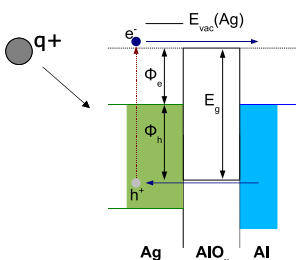


The EBIT beamline will offer:

- Highly charged ions:** various kinds of noble gases can be ionized up to the highest charge states with a Dresden Electron Beam Ion Trap
- Charge separation:** a bending sector magnet separates the emitted charge states
- Deceleration:** slowing down of the ions to kinetic energy  $< q \cdot 50$  eV
- SIMS/SNMS:** detection of secondary ions and neutral particles (laser post ionization) and emitted electrons (PIPS)

### Energy Scheme

- Electron hole pair creation by dissipation of kinetic and potential energy
- "Tunneling" current over and through the oxide barrier into the bottom Al electrode

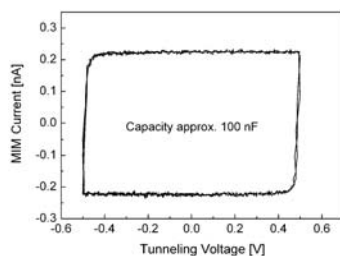


- Typical values of the MIM:
- work function of Ag: 4.3 eV
  - barrier height  $\Phi_b$ : approx. 3 eV
  - band gap  $E_g$  of the oxide: approx. 7 eV
  - thickness of Ag film: 25 nm
  - thickness of oxide film: 3 nm

### Stability of MIM devices

Measurement of resistance and capacity of the MIM

- MIM remains stable under several hundred shots
- Sputtering does not influence the measurement of subsequent shots



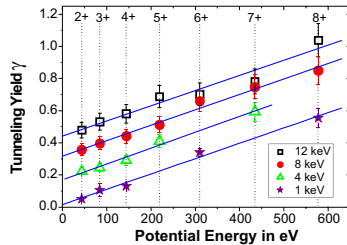
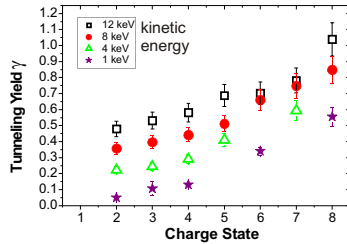
## Internal Electron Emission

### Measurements

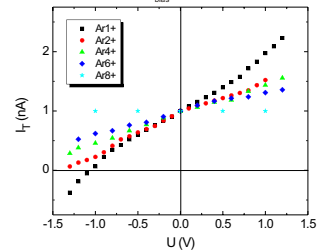
MIM under irradiation with  $Ar^{n+}$  of different  $q$ , but with constant kinetic energy

single shots ( $t = 150$  ms,  $I$  approx. 1 nA):

- Tunneling yield (e per projectile) at  $U_{bias} = 0$  V:



- Effect of kinetic and potential projectile energy can be clearly separated from each other
- Tunneling yield increases linearly with the potential energy with a factor of  $10^{-3}$  eV
- Yield increases linearly with the kinetic energy with  $0.4 \cdot 10^{-4}$  eV
- Relative yield at different bias voltages normalized to  $U_{bias} = 0$  V:



- Decreasing influence of bias voltage with increasing charge state
- Indication of higher electronic excitation

Work in collaboration with D. Kovacs, D. Diesing, A. Golczewky, F. Aumayr; see Peters et al., *Hot electrons induced by slow multiply charged ions*, New J. Phys. **10** (2008) 073019

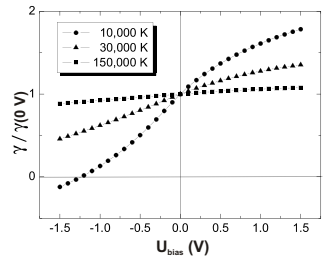
### Model: Local Electronic Temperature

(Cooperation with A3: D. Kovacs and D. Diesing)

Yield can be explained by a locally heated electronic system:

- Electrons excited by Auger transitions scatter with other electrons
- Energy distribution of excited electrons and holes reaching the barrier can be described by a Fermi-Dirac-function
- Current density of electrons and holes overcoming the barrier can be calculated by an assumption that local heating of a free electron gas in the top metal film causes internal electron emission (see Kovacs et al., *Potential electron emission induced by multiply charged ions in thin film tunnel junctions*, PRB **77** (2008) 245432)

- Calculated normalized tunneling yield of a hot electronic system in the top electrode:



## Outlook: Sputtering

### Central Idea

- Excitation & ionization of emitted particles is not understood very well
- Theoretical ionisation models:

$$\alpha^+ \propto \exp\left[-\frac{V_0}{V}\right] \quad \alpha^+ \propto \exp\left[-\frac{I - \Phi}{kT_e}\right]$$

Non-adiabatic models<sup>1)</sup>      substrate excitation models<sup>2)</sup>

- Significant parameter:

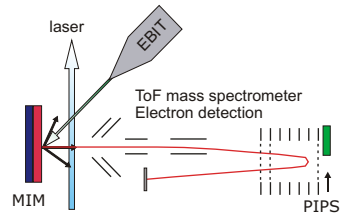
Electron temperature  $T_e$

→ Variation of  $T_e$  by changing projectile charge state at constant kinetic energy

- Total sputtering yield depends on  $E_{ion}$ , not on  $E_{pot}$  (and  $q$ , respectively)<sup>3)</sup>  
→ **Particle dynamics unaffected!**
- Electron emission depends strongly on  $q$   
→ **local excitations strongly influenced**

### Experiment

Time-of-Flight mass spectrometry with laser post ionization  
→ secondary ions only (laser off)  
→ neutral particles and ions (laser on)



- Local excitation by potential energy of the projectile
- Measurement of excitation and ionization probabilities of sputtered particles in dependence of  $q$  ( $T_e$ )  
→ Proof of ionization model
- Measurement of external and internal electron emission with PIPS and MIM

1) M.L. Yu et al. in "Sputtering by Particle Bombardment Vol III, 91  
2) Z. Šroubek et al., Vacuum **56** (2000) 263  
3) Aumayr et al., Phil. Trans. Royal Soc. London A, 362 (2004) 77